

- Topics :-

- Intrinsic
- Extrinsic
- Recombination
- Drift & Diffusion
- Continuity
- PN, Fwd, Rev
- Metal Semi (Skotch, Ohmi)
- Photo-diode
- LED

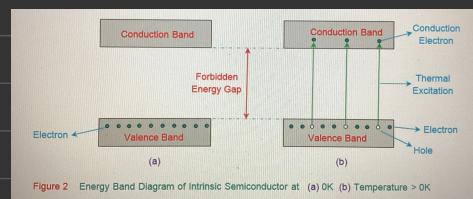
- Intrinsic Semiconductors

Pure Semiconductors contain very small amt. of imp. Forbidden gap is present so conductivity not possible when \vec{E} applied

e.g. Si Ge

The no. of e^- excited from top of VB to bottom of CB can be calc by Fermi Dirac statistics

Fermi-level



The no. of free e^- s per unit Vol. is ' n ' in conduction band
The no. of holes per unit Vol. is ' p ' in val. band

Carrier density

$$n = 2 \left[\frac{2\pi m_e^* kT}{h^2} \right]^{3/2} e^{(E_F - E_C)/kT}$$

$$p = 2 \left[\frac{2\pi m_h^* kT}{h^2} \right]^{3/2} e^{(E_V - E_F)/kT}$$



$\therefore n = p$ in intrinsic

$$\cancel{\frac{1}{2} \left[\frac{2\pi m_e^* kT}{h^2} \right]^{3/2} e^{(E_F - E_C)/kT}} = \cancel{\frac{1}{2} \left[\frac{2\pi m_h^* kT}{h^2} \right]^{3/2} e^{(E_V - E_F)/kT}}$$

$$\left(\frac{m_e^*}{m_h^*}\right)^{3/2} = e^{(E_v + E_c - 2E_F)}$$

$$(e^{2E_F}) \left(\frac{m_e^*}{m_h^*}\right)^{3/2} = e^{(E_v + E_c)}$$

Taking log

$$E_F = \frac{3kT}{2} \log \left(\frac{m_h^*}{m_e^*}\right) + \frac{E_v + E_c}{2}$$

also $m_e^* < m_h^*$

$$E_F = 0 + \frac{E_v + E_c}{2}$$

• Extrinsic Semicon

These type of semicon have tri & penta imp doped in a tetravalent semicon to inc conductivity i.e inc free e⁻s

① Fermi - level in N-type

- i) Penta-valent impurity
- ii) eg P in Si semicon

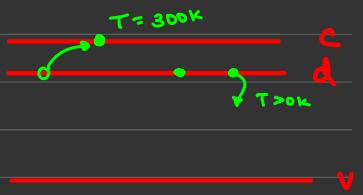
Suppose P is added to Si atom, 4/5 e⁻ in outermost orbital, this 5th e⁻ is loosely bound to parent atom, its called donor e⁻ and is close to lower lvl of CB.

Most of donor lvl e⁻ are excited into CB at room T & become majority charge carriers.

$$E_F = \frac{(E_c + E_d)}{2} + \frac{3}{2}kT \ln \left(\frac{N_d}{2 \left(\frac{2\pi m_e k T}{h^2} \right)^{3/2}} \right)$$

at $T = 0$

$$E_F = \frac{E_c + E_d}{2}$$

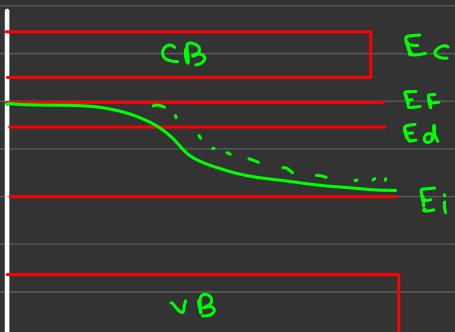


$T \uparrow$, Fermi-lvl \downarrow , donor ions \uparrow , e⁻-hole pair \uparrow

As T inc, Fermi lvl drops, for given T lvl \uparrow as conc. \uparrow

Further \uparrow in T results in gen. of e-h pair.

The Fermi lvl gradually move toward the intrin. fermi lvl.



② Fermi-level in P-type

- i) Tri-valent imp
- ii) eg Al is Si semi

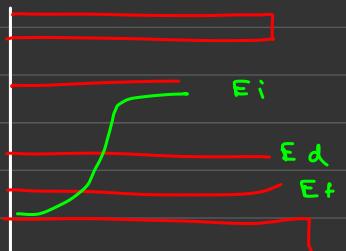
When Al doped with Si. 3 outermost e⁻ and the 4th extra e⁻ comes from neighbouring Si creating a hole

It energy lvl is close to top of VB at high T, e-h pairs are gen due to breaking of covalent bonds.

$$E_F = \frac{E_a + E_v}{2} + \frac{kT}{2} \ln \left(\frac{2 \left(\frac{2\pi M_h'' kT}{h^2} \right)^{3/2}}{N_A} \right)$$

at $T=0K$

$$E_F \approx E_v \approx E_a$$



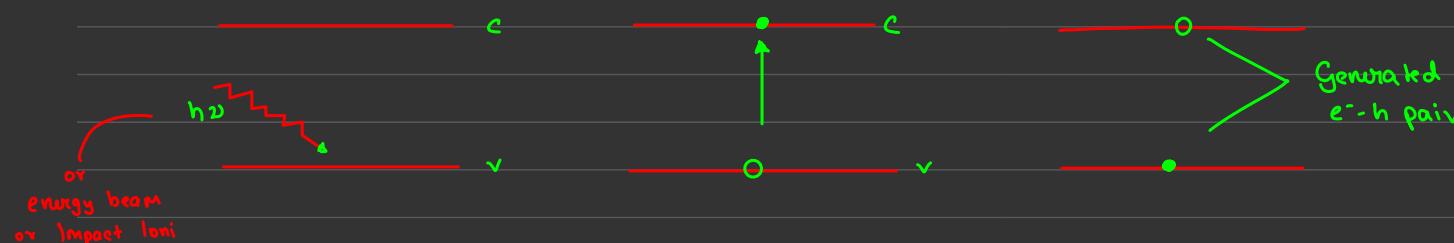
$T \uparrow, E_F \uparrow, \text{acceptor ions} \uparrow, e^- \text{-hole pair}$

further inc in T
 \uparrow tends to behave in
 intrin man

Carrier Generation and recombination

e^- in val. band get energy, they absorb it and jump to cond. band.

This e^- is called thermally generated free e^- and hole is generated



The process of falling back of thermally gen free e^- from cond. band in Val. band is called recombination of carriers

i) band to band recom

ii) Trap level (at some lvl than VB)

iii) Auger (energy released to next lower lvl till VB)



- Drift and Diffusion

When \vec{E} is applied to semicon $e^- + h$ acquire drift Vel (V_d) \propto to mag of \vec{E}

Holes move in directⁿ of \vec{E} while e^- move to opp directⁿ

This directional movement of carriers is known as drift current

$$V_d \propto \vec{E}$$

$$V_d = \mu \vec{E} \quad [\mu = \text{mobility of } e^- + h]$$

$$\begin{aligned} \text{Current density } J &= n_e V_d \\ &= n_e \mu E \end{aligned}$$

$$\therefore \text{For } e^- : J_n = n_e \mu_n E$$

$$h : J_p = p_e \mu_p E$$

$$\begin{aligned} \therefore \text{Total drift Current} : J &= J_p + J_n \\ &= n_e \mu_n E + p_e \mu_p E \end{aligned}$$

$$\text{for Int. Semi con} \quad n = p$$

$$\therefore J = [n_e (\mu_n + \mu_p)] E$$

$$J = \sigma E$$

$$\sigma = n_e [\mu_n + \mu_p]$$

Diffusion

Due to thermally induced random motion, charged particles move from high conc. to low conc.

Let, $\Delta n \rightarrow e^-$ conc. w dist. 'x'

$$\therefore \text{rate of } e^- \text{ flow} = \frac{\partial(\Delta n)}{\partial x}$$

$$\text{rate flow of } e^- \text{ across unit area} = D_n \frac{\partial(\Delta n)}{\partial x}$$

$$J_n (\text{diffusion}) = e D_n \frac{\partial(\Delta n)}{\partial x}$$

$$J_p (\text{diffusion}) = -e D_p \frac{\partial(\Delta p)}{\partial x}$$

$\Delta n \rightarrow$ diffusion coefficient

∂x

negative sign in front signifies that direction of hole current is opposite to the direction of the increasing conc. gradient.

Current density eq's

When E^T & conc. gradient is present across a semiconductor, both drift & diffusion current flow.

Total current density is:

$$\therefore \text{net } J_p = J_p \text{ drift} + J_p \text{ diffusion}$$

$$= ne \mu_p - e D_p \frac{d(\Delta p)}{dx}$$

$$p : \alpha_j = e$$

$$n : \alpha_j = -e$$

$$\text{net } J_n = n e \mu_n + e D_n \frac{d(\Delta n)}{dx}$$

• Continuity eq.

The overall effect when drift, diffusion, generation as well as recombination of carriers in a semicon is expressed by the cont. eq.

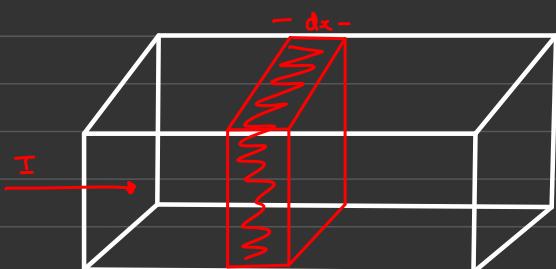
$$V = A \cdot d s$$

The rate of inc in no. of e^- s $\frac{\partial n}{\partial t}$ on the given vol. ($A \cdot d s$)

is given by algebraic sum of :-

Rate of flow in $\rightarrow x$
out $\rightarrow x + dx$

Generation $\rightarrow G_n$
Recom $\rightarrow R_n$



$$\frac{\partial n}{\partial t} A dx = \frac{J_n(x+dx) A}{q} - \frac{J_n(x) A}{q} + (G_n - R_n) A \cdot dx$$

$$\frac{\partial n}{\partial t} A dx = J_n \frac{(x+dx) A}{q} \cdot \frac{dx}{dx} - J_n \frac{(x) A}{q} \cdot \frac{dx}{dx} + (G_n - R_n) A \cdot dx$$

$$\frac{\partial n}{\partial t} A \cancel{dx} = \left[\frac{J_n(x+dx)}{q \cdot dx} - \frac{J_n(x)}{q \cdot dx} + G_n - R_n \right] A \cancel{dx}$$

$$\frac{\partial n}{\partial t} = \frac{1}{q} \left[\frac{J_n(x+dx)}{dx} - \frac{J_n(x)}{dx} \right] + G_n - R_n$$

$$\therefore dx \approx 0 ; J_n(x+dx) = J_n(x) + \frac{\partial J_n}{\partial x} \cdot dx$$

$$\frac{\partial n}{\partial t} = \frac{1}{q} \left[\cancel{\frac{J_n(x)}{dx}} + \frac{\partial J_n}{\partial x} \cdot \cancel{dx}/dx - \cancel{\frac{J_n(x)}{dx}} \right] + G_n - R_n$$

$$\frac{\partial n}{\partial t} = \frac{1}{q} \left(\frac{\partial J_n}{\partial x} \right) + G_n - R_n \quad [\text{for } e^-]$$

$$\frac{\partial n}{\partial t} = - \frac{1}{q} \left(\frac{\partial J_n}{\partial x} \right) + G_n - R_n \quad [\text{for holes}]$$

• Metal Semicon Junction

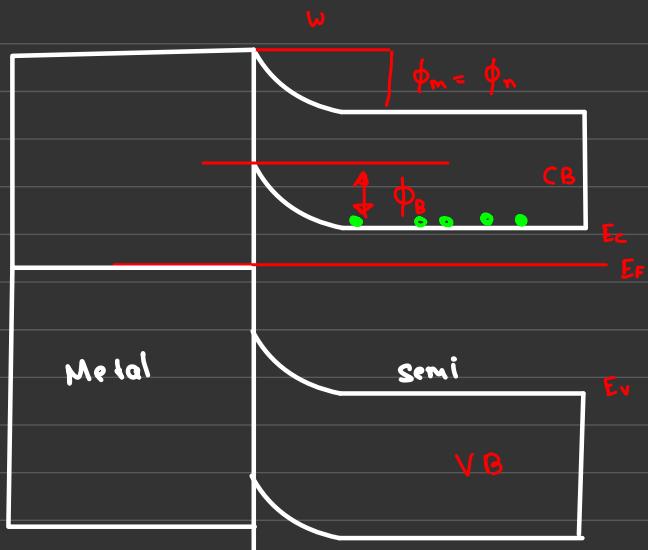
The type of electrical junction in which a metal comes in close contact to semicon mat

i) Rectifying Schottky Junction

Work functⁿ of n-type semicon is less than of metal

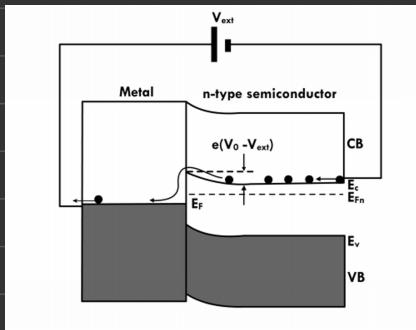
$$\phi_m > \phi_s$$

When the two come in contact, e- flow from semi to metal until E_f of both becomes equal so metal (-ve) & semi (+ve) as Potential barrier of $\phi_m - \phi_s = eV$

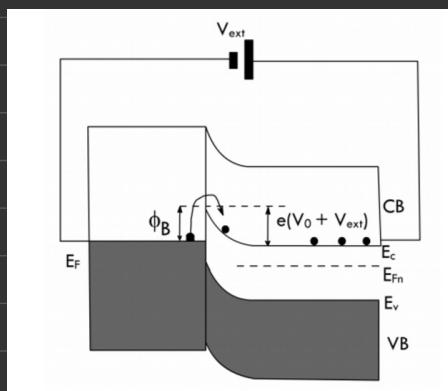


When potential is applied :-

c-1] N-type sem (+ve) & metal (-ve)
height of Pot. barr \uparrow by $(V_s + V)$ for semi
Metal remains unchanged
Reverse biased



c-2] sem (-ve) & met (+ve)
height \uparrow by $(V_s - V)$
Metal remain unchanged
forward biased

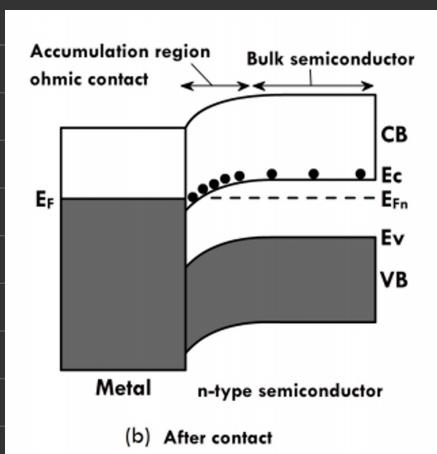


ii) Non-Rectifying Ohmic Junction

when ϕ_m of metal is less than n-type semi

$$\phi_m < \phi_s$$

When the two come in contact, e^- flow from metal to semi until E_F is equal, metal (+ve) & sem (-ve)
at pot. bar. $\phi_s - \phi_m = eV$



when voltage applied

C-1] Sem (+ve) & Met (-ve) \rightarrow no change to pot. barriers

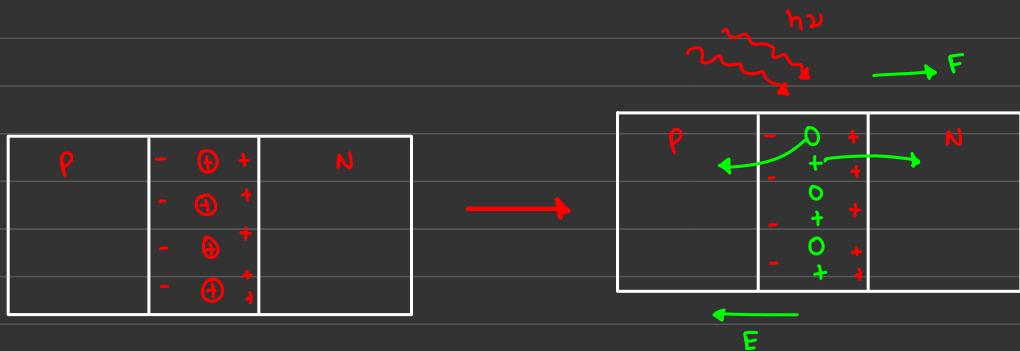
C-2] $-ve$ $+ve$ \rightarrow "

i.e. I & Applied Voltage \propto it's called ohmic contacts.

• Photodiode

In a photodiode, the incident optical signal generates e-h pair that gives rise to a photocurrent across PN junc. It is generated in RB cond"

• Working



When light of photon energy $\geq E_g$, the photons are absorbed.

This results in release of e^- from atom structure, free e^- & holes are gen both in n & p region.

They are swept across the junc due to E in depletion region

Due to directⁿ of E from n to p, hole flow in same directⁿ while e^- flow in opp i.e. to n region.

Thus, they constitute the photocurrent I_L as if directⁿ is opp to that in FB diode

$$\therefore I_L = I_{nL} + I_{pL} + I_d$$

Doubt

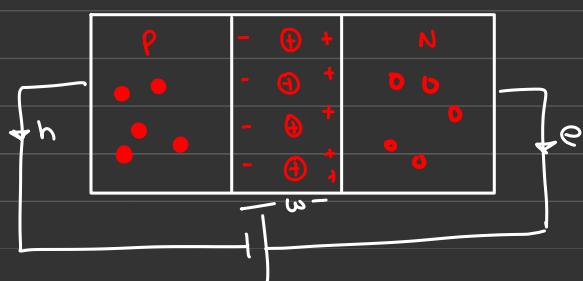
The photon absorption intensity \propto photon energy

This process is known as Inner Photoelectric Effect

$$I = eG_i \left(L_p + L_n + w \right) A_{\text{Area}}$$

width
dist of dep region
where e & h are gen

gen rate



- LED

LED (Light emitting diode) are P-N junctions that can emit spontaneous radiation in UV, Vis, IR regions.

This device converts elec to optical energy under FB cond'n

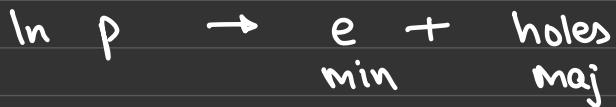
- Principle

Due to FB, maj cars from n & p regions cross the junc & become min cars

i.e. $e \rightarrow$ maj in n & min in p
 $h \rightarrow$ min in n & maj in p

This phenomenon is called minority carrier injection

If the biasing voltage is further inc, the \propto s min car diffuse away from junc & recombine with maj cars and emit light



This is called radioactive recombination.

It leads to photon emission w energy equal to $h\nu$

Rad. Recom \propto Carrier Injectn rate

$$(I = I_0 \left[\frac{\exp(\frac{ev}{kT}) - 1}{\ln(1 - 2)} \right])$$

Total curr Sat. curr

• Types

LEDs are constructed in such a way that the light emitted by rad. recomb shld escape the structure

1) **Surface Emitters** : designed to reflect light from bottom edge to top surface to enhance output intensity,

2) **Edge Emitters** : Here light emission is relatively direct from one active region or depletion region.

• Quantum Efficiency

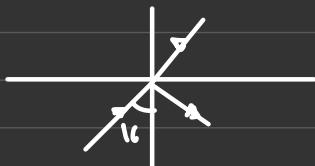
Internal quantum efficiency is 100% but external dec becoz the emitting light strikes the surface at an angle greater than critical angle causing TIR and gets trapped within

for TIR

$$\theta_c = \sin^{-1} \left(\frac{n_2}{n_1} \right)^{\text{air}}$$

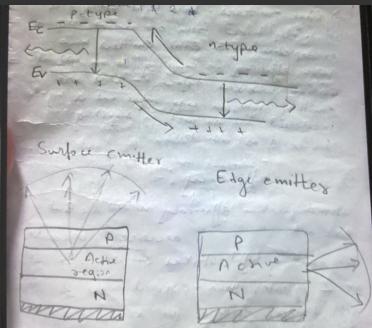
$$\text{eg } n_1 = 3.5$$

$$\theta_c = \sin^{-1} \left(\frac{1}{3.5} \right) = 16^\circ$$



The ray strikes the surface above 16° so it suffers TIR & is ref back

Note To improve external efficiency loss caused by bulk absorption, hemispherical domes made of plastic are fused at the surface.



• OLED

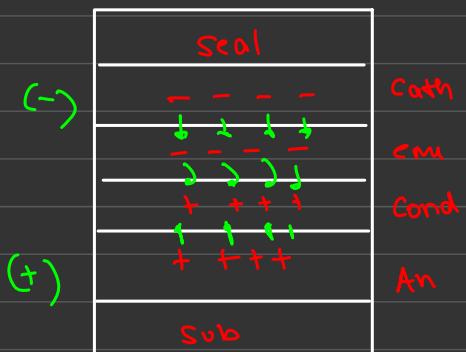
A type of LED where electroluminescent layer is a film of org. comp which can emit light in response to elec. current.

• Structure

Top & bottom layers are of protective glass / plastic (seal & substrate)

In b/w there Cathod (inject e-) & Anode (ejects holes)

In b/w those , there is an emissive & conductive layer



OLED emit light thru a process called electro phosphorescence

• Working

A power supply applies V across OLED

Current flows frm Cath to Ano , Cath gives e⁻ to emm layer and Anode removes e⁻ from cond layer

At the boundary the emm & cond e⁻ find holes & fills emitting energy as photon or light

Intensity of light ↑ , Current ↑

Types of OLED

- ↳ Passive matrix OLED - have strips of (PMOLED) of cathode, an organic layer & strips of ~~anode~~ anode that run perpendicular.
Advantage - easy fabrication, suitable for small screen.
- ↳ Active matrix OLED - organic layer is b/w larger layers of cathode & anode.
Advantage - Less power requirements., suitable for large screen.

Advantages : -

less expensive, thinner compared to LED,
less in weight, flexible, consumes
less power, response time is 2x faster than
LED.

Disadvantages : -

organic molecules are sensitive to water
display doesn't last for too long.

Applications : -

wrist watches, head sets, TV, camera,
MP3 players, etc.